

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masayuki ASAI et al.

Application No.: 09/670,021

Filed: September 26, 2000

Attn: Box Missing Parts

Docket No.: 107428

For: PLASMA CVD SYSTEM AND PLASMA CVD FILM DEPOSITION METHOD

RESPONSE TO NOTICE TO FILE MISSING PARTS WITH DECLARATIONDirector of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

In response to the Notice to File Missing Parts of Application - Filing Date Granted (copy attached) mailed on November 1, 2000, submitted herewith is the executed Declaration of the inventor(s). Any specification attached to and referenced in the Declaration is a copy of the specification and any amendments thereto which were filed in the Office in order to obtain a filing date for the application.

Attached is our Check No. 113906 for ☒\$130.00 ☐\$65.00 (entitlement to small entity status is asserted) for the fee under 37 C.F.R. §1.16(e).

Entry of these documents should complete all of the filing formalities and fully satisfy all requirements of the Notice to File Missing Parts. Accordingly, examination and allowance of this application in due course are respectfully solicited.

The Director is hereby authorized to charge any additional fee (or credit any overpayment) associated with this communication to Deposit Account No. 15-0461. Two duplicate copies of this paper are attached.

Respectfully submitted,

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JAO:TJP/mgs

Date: November 21, 2000

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| DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461 |
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